

Advertisement for the post of Research Associate (RA) position in the project of MEMS based Piezo Sensors

Date of Advertisement: 18/08/2023

Applications are invited from the Indian nationals for the post of Research Associate in the area of Micromachining and MEMS with relevant prior experience.

Name of the post	Research Associate (RA)
Number of vacancies	1
Sponsored Project	<i>Fabrication of high temperature piezo pressure sensor for Aeronautical applications</i>
Salary	Rs. 49000/- + HRA (if hostel is not provided)
Appointment period	24 months (extendable up to the closure of project.) Note: <ol style="list-style-type: none">1. Monthly fellowship will be released after monthly progress review report.2. In case of unsatisfactory progress, the candidate may be asked to leave after giving one-month notice.
Essential Qualification	<ol style="list-style-type: none">1. PhD with BE/BTech/MTECH/Equivalent in /EE/Physics/other relevant branches with research focus in the area of MEMS fabrication. Candidate with relevant experience and publication in standard MEMS journals will have added advantage.2. Candidate should have good academic records throughout and good writing skills.

Age limit:	Maximum 40 years as on the day on which the application is made. The upper age limit is relaxable upto 3 years in the case of candidates belonging to scheduled castes/tribes/OBC, women and physically handicapped candidates.
Job Description	- Collection of relevant literatures

	<ul style="list-style-type: none"> - Microfabrication processes such as wafer cleaning, thin film deposition, photolithography, wafer bonding, etching of silicon and glass wafers. - Characterization of microstructures using different tools such as SEM, Ellipsometry, optical microscope..etc - Expertise in TCAD tools - Report preparation and lab management. - Interaction with sponsored agencies, .
Application Procedure	<p>Candidates are required to send following documents in a single pdf file</p> <ol style="list-style-type: none"> 1. Latest CV with marks percentage, experience, and a list of patents and publications. 2. Certificates/Transcripts with clear mention of discipline, percentage marks and date of birth. 3. Statement of purpose stating relevant experience towards the project. 4. At least one best publication in relevant area. <p>to Email: sgsingh@ee.iith.ac.in with subject line “Application for RA position in the Project MEMS based Piezo pressure sensors ” by 24th August 2023 (5:00 PM).</p>
Selection Procedure	<p>Candidates will be shortlisted based on the eligibility criteria, academic record, and relevant experience. Only, shortlisted candidates will be intimated through email for the online interview by the selection committee. Merely meeting the criteria may not guarantee a call for an interview. The position will be left vacant and new advertisement with extended date will be given if no suitable candidate is found.</p>

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